

Notice of References Cited

Application/Control No.

10/067,711

Applicant(s)/Patent Under
Reexamination
SZCZYRBOWSKI ET AL.

Examiner

Steven H VerSteeg

Art Unit

1753

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,415,757	05-1995	Szcyrbowski et al.	204/298.08
	B	US-5,169,509	12-1992	Latz et al.	204/298.03
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Scherer et al., "Reactive alternating current magnetron sputtering of dielectric layers", pp. 1772-1776 (1992)			
	V	Vossen et al., "Thin Film Processes", pp. 61-62 (1978)			
	W				
	X				

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.